

ABSTRACT OF THE DISCLOSURE

[0010] An electrically actuated micro-mirror system is disclosed. The system has at least three supporting springs attached to a micro-mirror providing at least two rotational degrees of freedom thereof. At least two optional enhancement springs are fanned out from an associated supporting spring to secure the micro-mirror, and the micro-mirror is electro-statically actuated to rotate while the supporting springs and the enhancement springs operate primarily in a tensile mode.